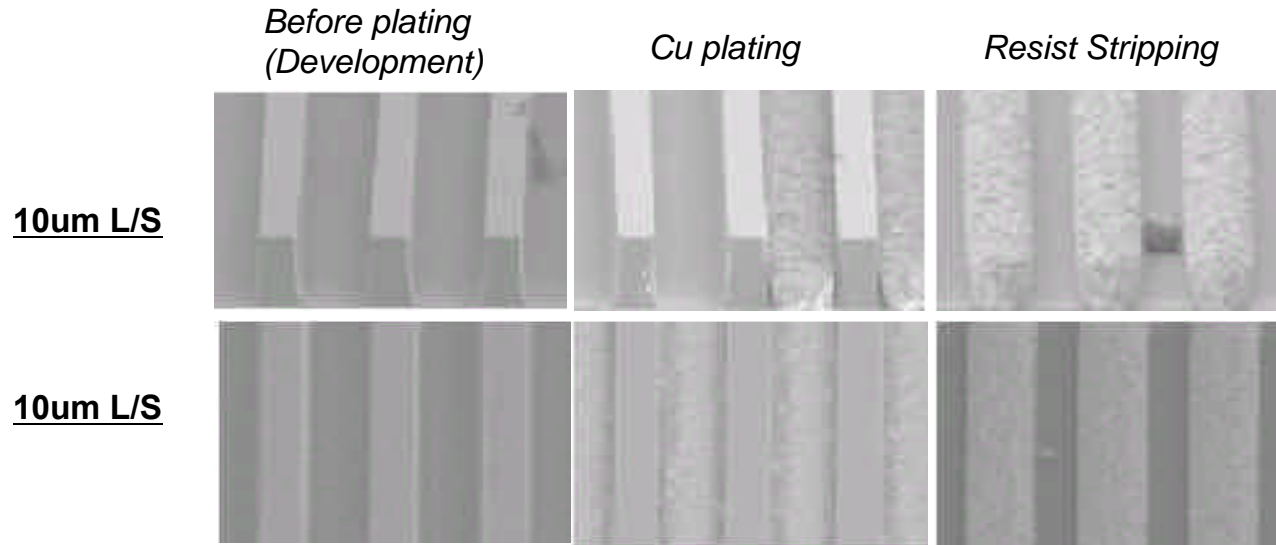




# AZ<sup>®</sup> P4620 Photoresist Data Package

The information contained herein is, as far as we are aware, true and accurate. However, **no representations or warranties, either express or implied, whether of merchantable quality, fitness for any particular purpose or of any other nature are hereby made in respect of the information contained in this presentation or the product or products which are the subject of it.** In providing this material, no license or other rights, whether express or implied, are given with respect to any existing or pending patent, patent application, trademarks, or other intellectual property right.

# AZ P4620 Copper plating



## Plating process condition

Photoresist thickness: **15um**, Prebake: 110C/180 sec. (Hotplate)

Exposure: PLA-501F ( Soft contact, ghi-line aligner)

Development: AZ 400K 1:4, Immersion for 300 sec., 23 C

Plating liquid: **MICROFAB Cu200** (EEJA)

Plating height: 7.0um, Plating: 25 C / 30 min.

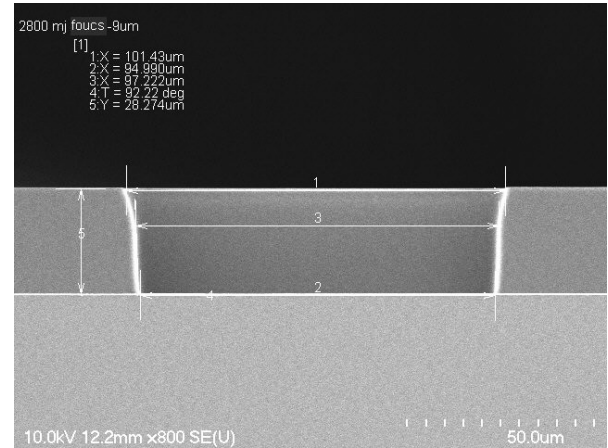
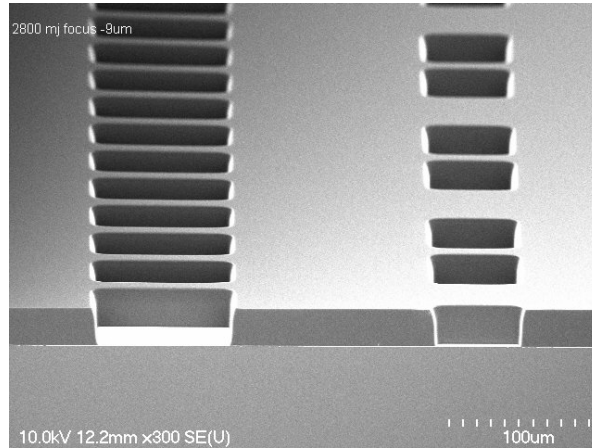
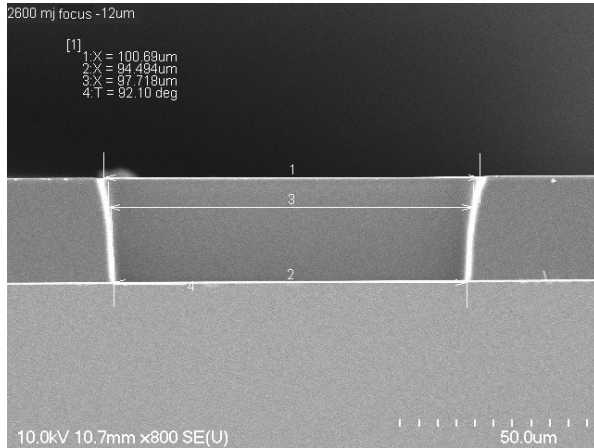
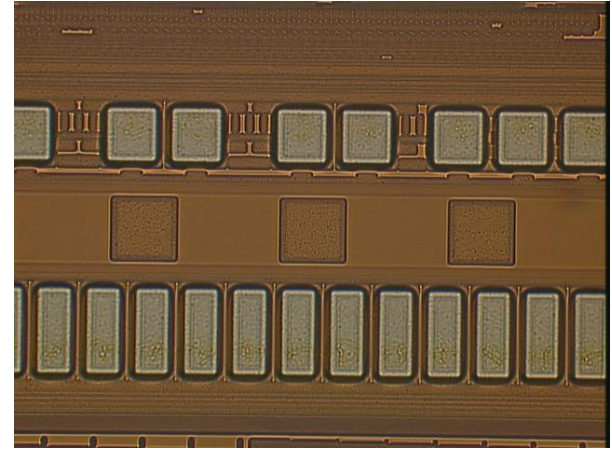
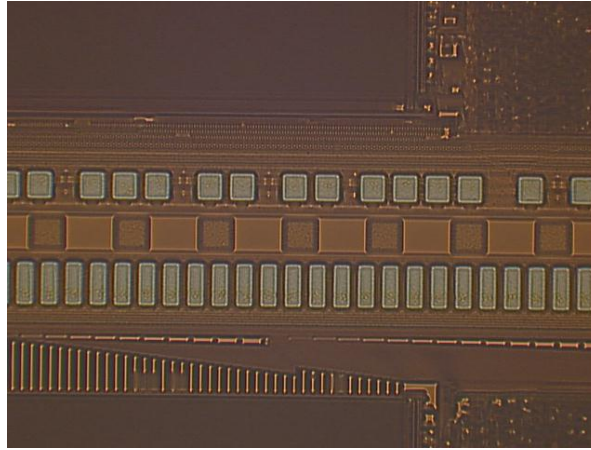
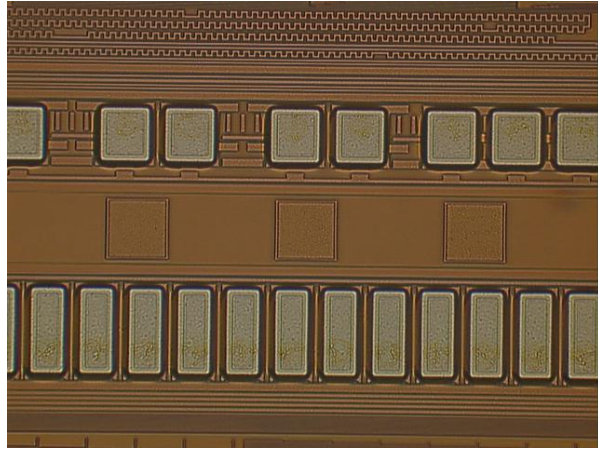
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# AZ<sup>®</sup> P4620 Gold Plating Process

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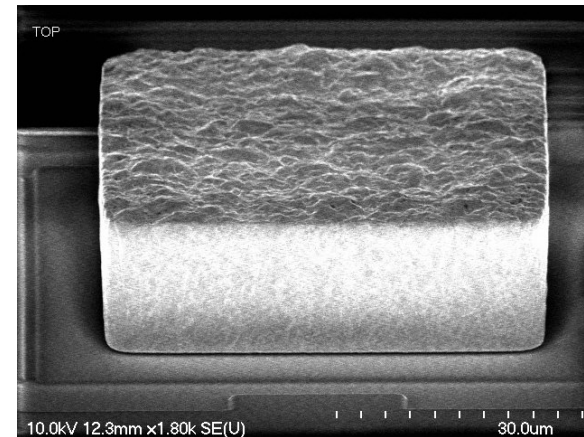
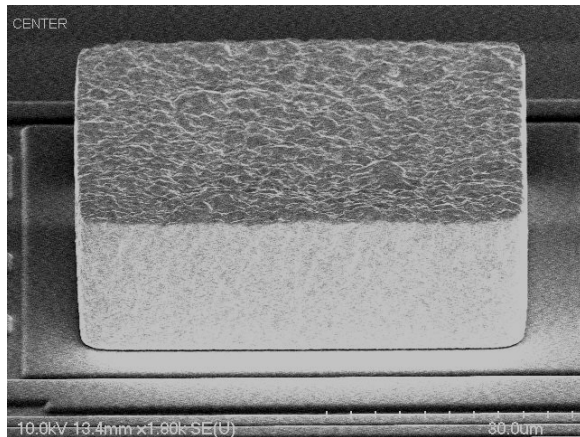
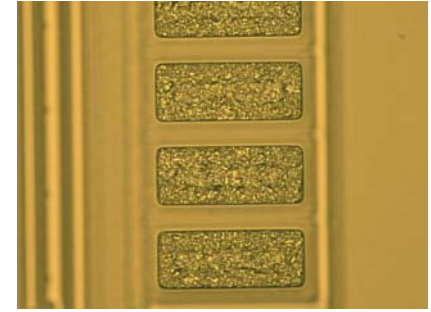
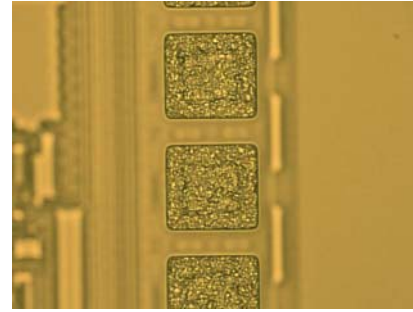
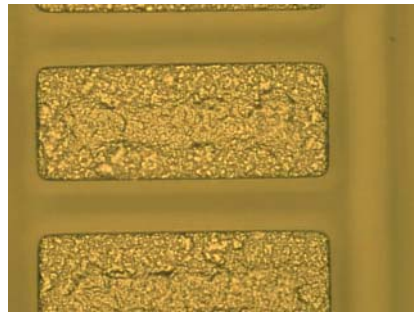
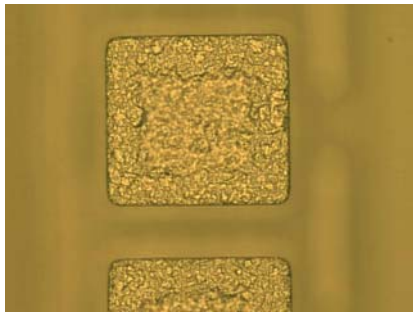
FT: 28um, Single Coat  
Softbake: 1) 100°C / 500 sec. (Hotplate)  
2) 90°C / 180 min. (Oven)  
Rehydration time: 60 minutes  
Exposure: UTS-SS-III (ghi-line)  
Develop: AZ 400K 1:3, 21.5°C  
Plating: Cyanide Gold Plating Solution

# AZ<sup>®</sup> P4620 Gold Plating Process



# AZ<sup>®</sup> P4620 Gold Plating Process

Photoresist Mask CD = 93.5 $\mu$ m; Au Bump CD = 96 $\mu$ m.



# AZ P4620 Lithography performance

## Process Conditions:

Optitrac Coat/ Bake

Coat: Static dispense on Silicon

Target Film Thickness: **12  $\mu\text{m}$**

Softbake: 110C hotplate/ 80 sec. full contact

Exposure: Ultratech 1500 gh line Stepper

Develop: AZ<sup>®</sup> 300 MIF, continuous spray for 200 sec. @ 23 C

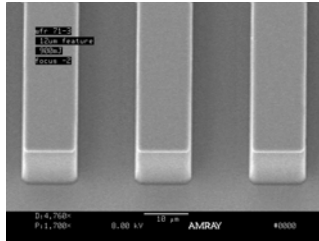
## Analysis:

Amray SEM

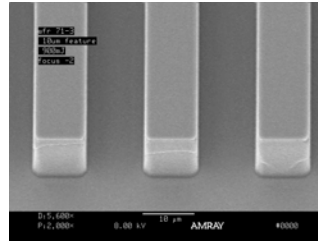
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# AZ P4620 Lithography performance

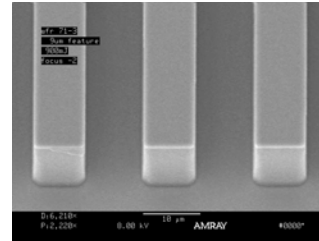
12  $\mu\text{m}$



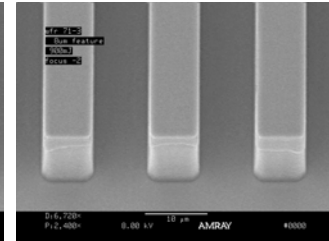
10  $\mu\text{m}$



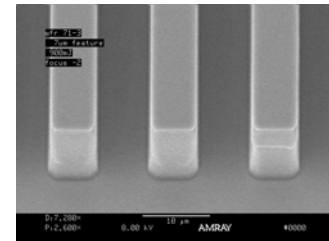
9.0  $\mu\text{m}$



8.0  $\mu\text{m}$

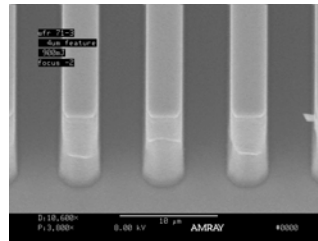


7.0  $\mu\text{m}$

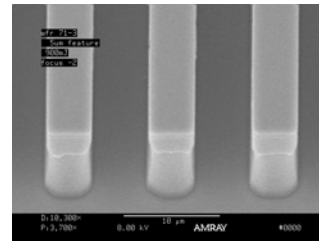


Film Thickness: **12  $\mu\text{m}$**   
 Optitrac coat and Bake  
 SB: 110 C / 80 sec  
 Ultratech 1500 gh line Stepper  
 AZ 300 MIF, 200 sec continuous spray @ 23 C

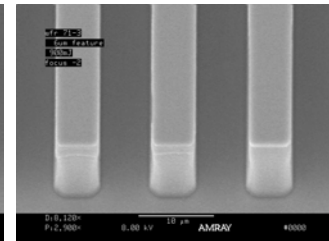
4.0  $\mu\text{m}$



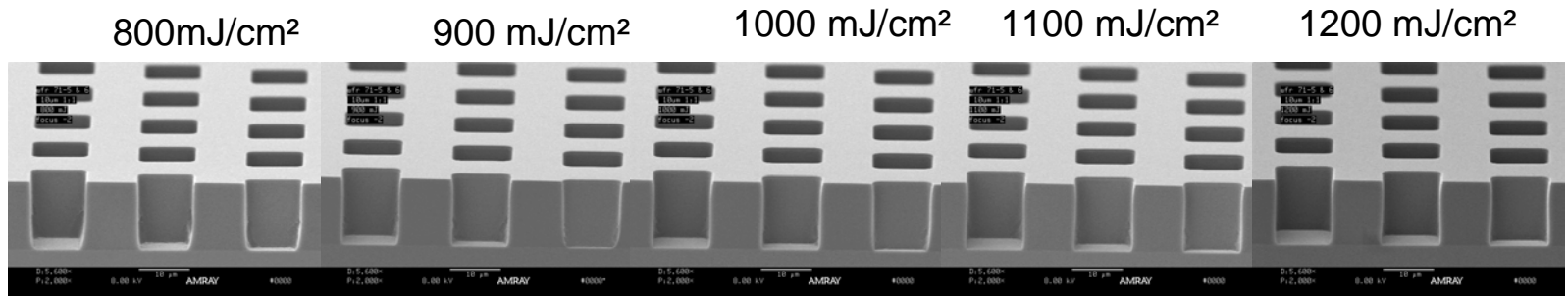
5.0  $\mu\text{m}$



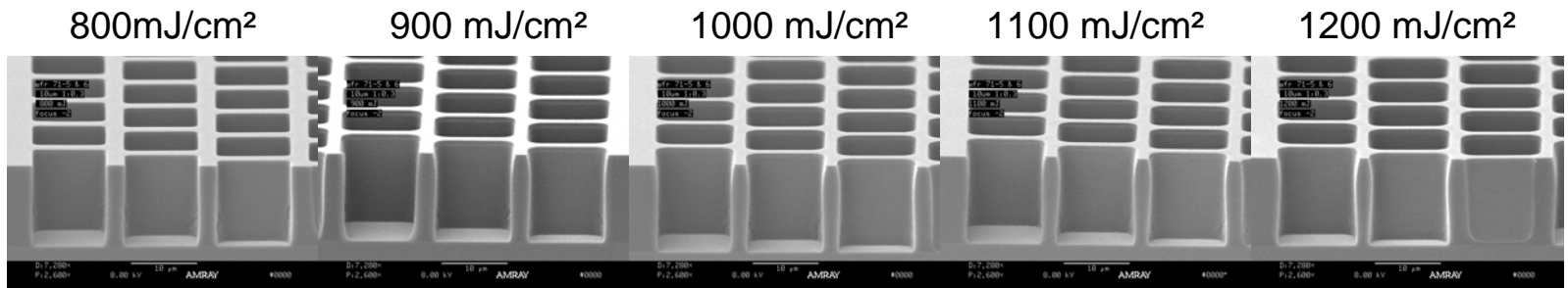
6.0  $\mu\text{m}$



# AZ P4620 Lithography performance



10.0 μm Contact Holes 1:1 Pitch



10.0 μm Contact Holes 1:0.3 Pitch

Film Thickness: **12 μm**  
 Optitrac coat and Bake  
 SB: 110 C / 80 sec  
 Ultratech 1500 gh line Stepper  
 AZ 300 MIF, 200 sec continuous spray @ 23 C



# AZ P4620 Lithography performance

## Process Conditions:

Optitrac Coat/ Bake

Coat: Static dispense on Silicon

Target Film Thickness: **24  $\mu\text{m}$**

Softbake: 1<sup>st</sup> layer 110 C hotplate/ 80 sec. full contact

2<sup>nd</sup> layer 115 C hotplate/ 180 sec. full contact

Exposure: Ultratech 1500 gh line Stepper

Develop: AZ<sup>®</sup> 400K 1:4, continuous spray for 260 sec. @ 27 C

## Analysis:

Amray SEM

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# AZ P4620 Lithography performance

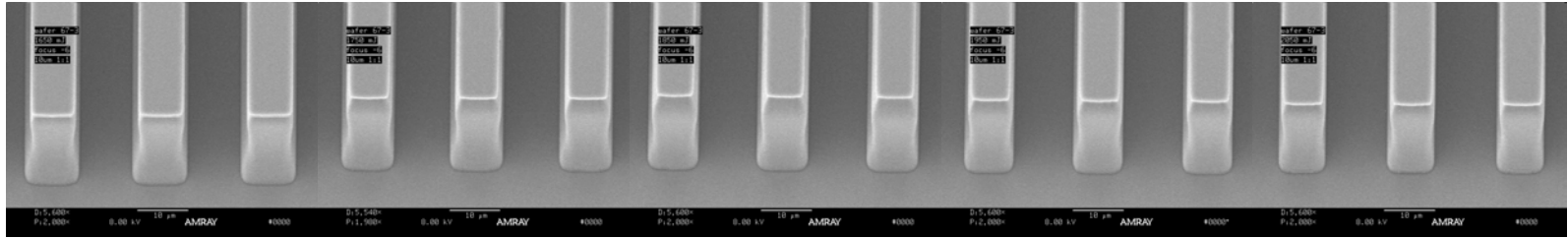
1650 mJ/cm<sup>2</sup>

1750 mJ/cm<sup>2</sup>

1850 mJ/cm<sup>2</sup>

1950 mJ/cm<sup>2</sup>

2050 mJ/cm<sup>2</sup>



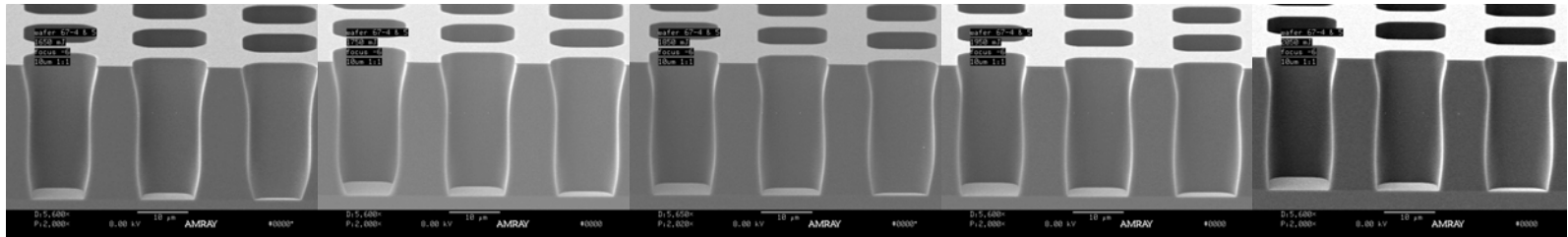
1650 mJ/cm<sup>2</sup>

1750 mJ/cm<sup>2</sup>

1850 mJ/cm<sup>2</sup>

1950 mJ/cm<sup>2</sup>

2050 mJ/cm<sup>2</sup>



Film Thickness: 24 µm

Optitrac coat and Bake

SB: 1<sup>st</sup> layer 110 C / 80 sec

2<sup>nd</sup> layer 115 C / 180 sec

Ultratech 1500 gh line Stepper

AZ 400K 1:4, 260 sec continuous spray @ 27 C

# AZ<sup>®</sup> P4620 Lithographic Performance Summary

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## Process Conditions

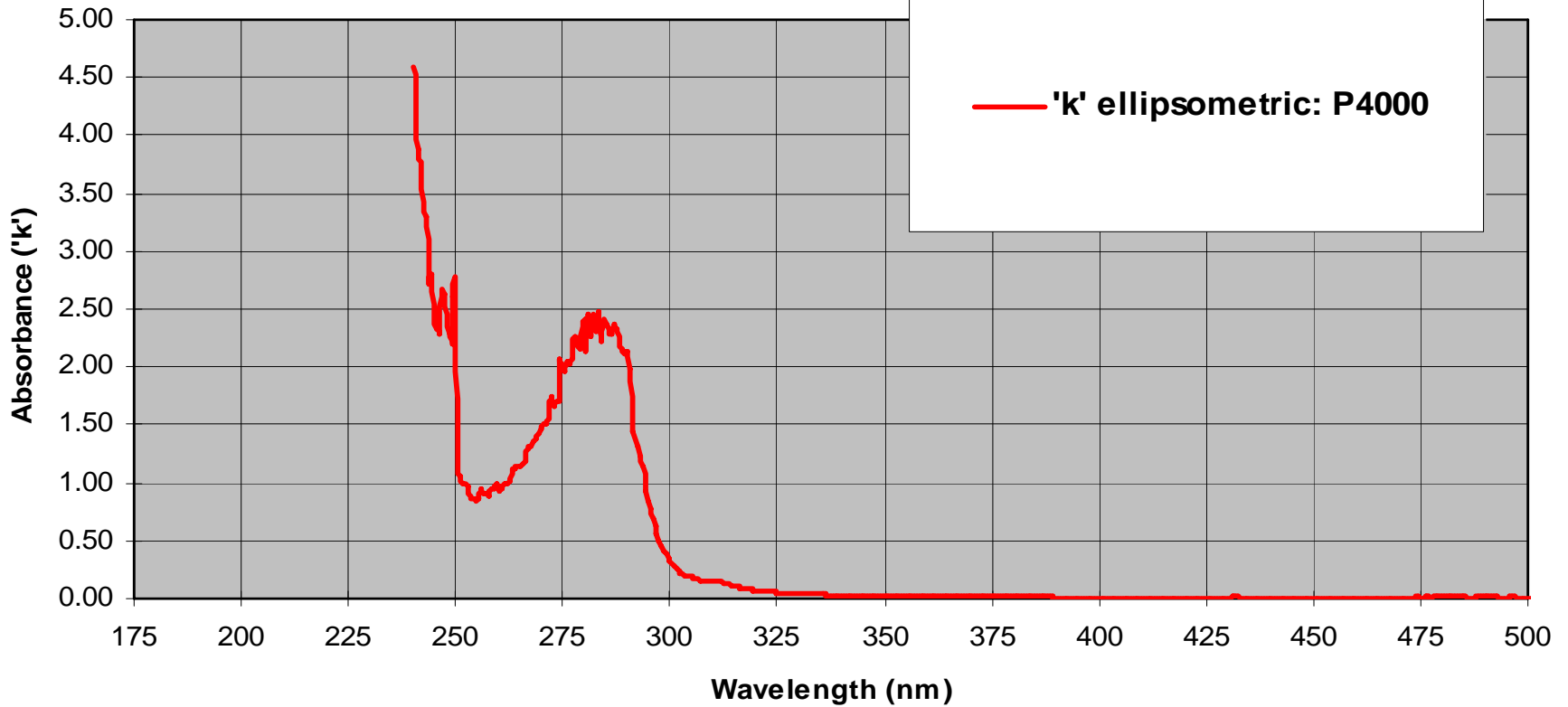
Substrate :	Bare-Si
Film-thickness :	17 $\mu$ m
Softbake :	120 $^{\circ}$ C / 240 sec. (DHP)
Exposure :	Canon PLA-501F (ghi-line)
Dose :	630 mJ/cm <sup>2</sup>
Development :	AZ 400K Developer 1:4, Immersion - 300 sec., 23 $^{\circ}$ C





# AZ<sup>®</sup> P4000 Bleached Absorbance Curve

AZ P4000 Series resist(s)  
Ellipsometric Absorbance  
Normalized to 1/ $\mu\text{m}$

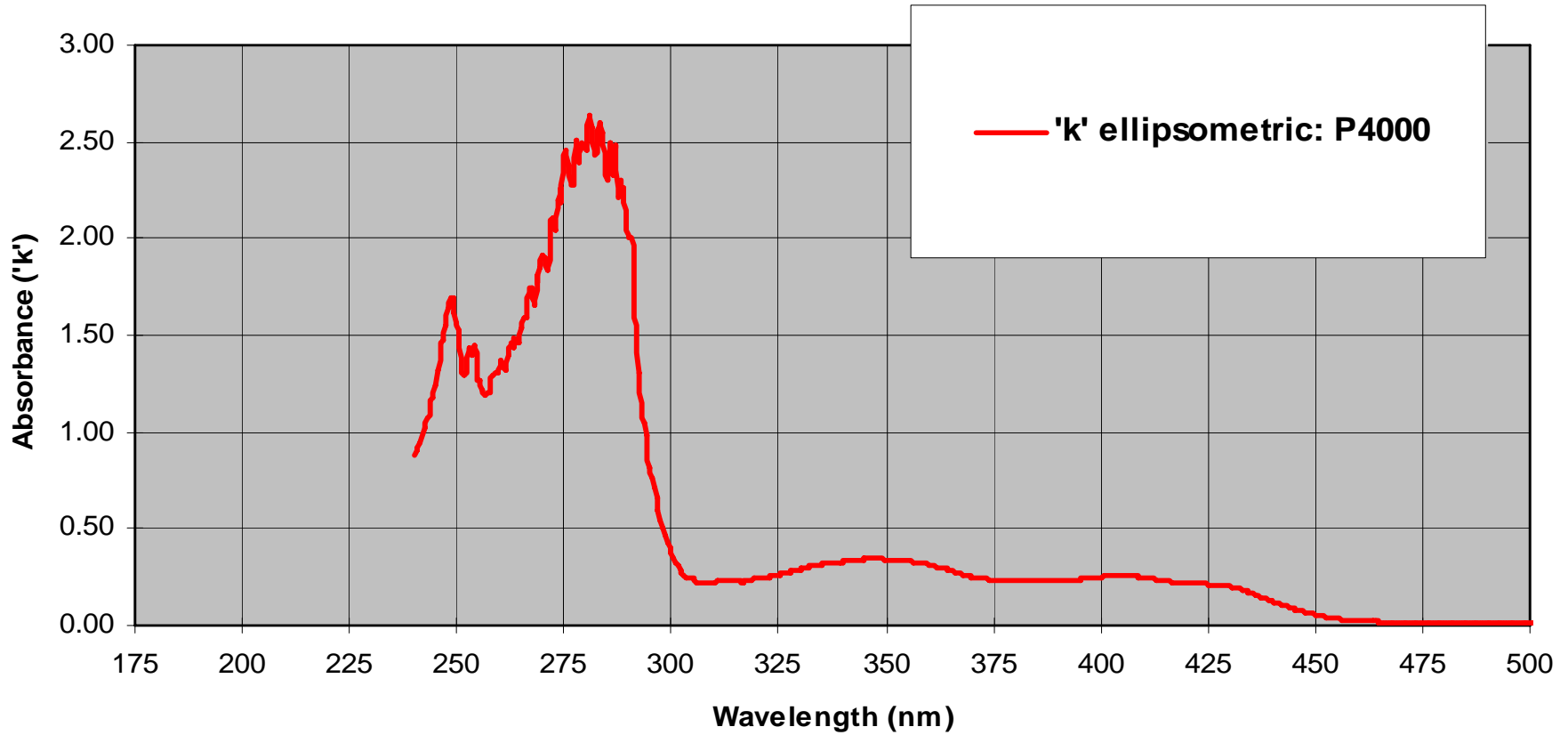


— 'k' ellipsometric: P4000



# AZ<sup>®</sup> P4000 Unbleached Absorbance Curve

AZ P4000 Series resist(s)  
Ellipsometric Absorbance  
Normalized to 1/ $\mu$ m



# AZ<sup>®</sup> P4000 Series Spin Speed Curve

